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## HE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Confirmation No. 6344

Yoshio YANASE et al.

Docket No. 2001-0615A

TC 2800 MAIL ROOM

Serial No. 09/856,982

Group Art Unit 2877

HAR 21 20

Filed May 30, 2001

Examiner Sang H. Nguyen

METHOD FOR INSPECTING SEMICONDUCTOR WAFER SURFACE

## PETITION FOR EXTENSION OF TIME

Assistant Commissioner for Patents, Washington, DC 20231

THE COMMISSIONER IS AUTHORIZED TO CHARGE ANY DEFICIENCY IN THE FEES FOR THIS PAPER TO DEPOSIT ACCOUNT NO. 23-0975

Sir:

Petition hereby is made for a two month extension of time to respond to the communication of October 15, 2002.

The fee of \$410.00 is

- (X) submitted herewith.
- to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.
- O Small entity status of this application is established by a Small Entity Status Assertion which
  - () is enclosed.
  - () has been previously submitted.

Respectfully submitted,

Yoshio YANASE et al.

Ву

Joseph M. Gorski Registration No.46,500 Attorney for Applicants

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